AMENDMENTS TO THE CLAIMS

1. (Withdrawn)

2. (Withdrawn)

3. (Withdrawn

4. (Withdrawn))

5. (Withdrawn)

6. (Withdrawn)

7. (Withdrawn)

8. (Withdrawn)

9. (Withdrawn)

10. (Withdrawn)

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11. (Currently Amended) An apparatus having ~~at least one~~ a sealed microchannel therein, comprising:

~~a first~~ an etched substrate,

~~at least one~~ an etched microchannel in said ~~first~~ etched substrate,

~~a second~~ an annealed substrate positioned on said ~~first~~ etched substrate that covers said ~~at least one~~ etched microchannel in said ~~first~~ etched substrate,

~~a corresponding at least one~~ an annealed microchannel in said ~~second~~ annealed substrate ~~immediately above said at least one~~ covering said etched microchannel in said ~~first~~ etched substrate, and

a bond connecting said ~~first~~ etched substrate and said ~~second~~ annealed substrate, wherein said ~~at least one~~ etched microchannel and said ~~at least one~~ annealed microchannel comprise said ~~at least one~~ sealed microchannel.

12. (Currently Amended) The apparatus of Claim 11, wherein said ~~at least one sealed microchannel has no sharp corners therein~~ annealed microchannel is a high temperature annealed microchannel annealed in the 600° to 800° range.

13. (Currently Amended) The apparatus of Claim 11, wherein said ~~at least one~~ etched microchannel in said ~~first~~ etched substrate and said ~~corresponding at least one~~ annealed microchannel in said ~~second~~ annealed substrate form a circular ~~at least one~~ sealed microchannel.

14. (Currently Amended) The apparatus of Claim 11, wherein said ~~first~~ etched substrate and said annealed substrate ~~is~~ are selected from the group consisting of glass members, glass and silicon members, glass and polymer members, and members selected from the group of glass, silicon and polymers.

15. (Previously Amended) The apparatus of Claim 11, wherein said bond comprises fusion or anodic bonding.

16. (Currently Amended) The apparatus of Claim 11, wherein said ~~second substrate is selected from the group consisting of glass members, glass and silicon members, glass and polymer members, and members selected from the group of glass, silicon and polymers~~ annealed microchannel has depth of about 10 μm and a width of about 20 μm and said annealed microchannel is a high temperature annealed microchannel annealed in the 600° to 800° range.